

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TETSUKA, et al.
Serial No.: Not yet assigned
Filed: February 24, 2004
For: PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING
METHOD

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98

Mail Stop DD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 24, 2004

Sir:

In the matter of the above-identified application, applicants are submitting herewith a copy of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration.

This information disclosure statement is being submitted with the new application.

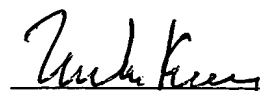
Although some of the documents listed on the attached form equivalent to Form PTO-1449 are not in the English language, the requirement of 37 CFR 1.98(a)(3) for a concise explanation of the relevance is satisfied by the discussion of the documents in the specification, for example, on page nine (9).

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of Antonelli, Terry, Stout & Kraus Deposit Account No. 01-2135 (Case: 648.43518X00), and please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS LLP



Melvin Kraus
Registration No. 22,466

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Attachments

Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DKT. NO. 648.43518X00	SERIAL NO.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		APPLICANT TETSUKA, et al.	
		FILING DATE February 24, 2004	GROUP

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date
AA						
AB						
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AD						
AE						
AF						
AG						
AH						
AI						
AJ						
AK						
AL						

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Abstract	
						Yes	No
AM	2001-23967	01/26/2001	JP	H01L	21/3065	X	
AN	2001-267299	09/28/2001	JP	H01L	21/3065	X	
AO							
AP							
AQ							
AR							
AS							
AT							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

AU	M.A. Lieberman, Translated by H. Sato, "Principles of Plasma Discharges and Materials Processing", Published November 20, 2001 by ED Research Co., Page 116
AV	
AW	
AX	
AY	
AZ	
Examiner	Date Considered